Docket No.: 57810-074 **PATENT**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277

Isao Hasegawa, et al. : Confirmation Number:

Serial No.: : Group Art Unit:

Filed: September 11, 2003 : Examiner: Unknown

For: METHOD OF FABRICATING SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Mail Stop IDS Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

The relevance of AM-LCD '02, Digest of Technical Papers, July 10-12, 2002, pp. 227-230 is discussed in the present specification.

Serial No.:

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

Anthur J. Steiner

Registration No. 26,106

600 13th Street, N.W.

Washington, DC 20005-3096 (202) 756-8000 AJS:tlb

Facsimile: (202) 756-8087 **Date: September 11, 2003**

INFO		TION DISCLO	SURE	ATTY. DOCKET NO. 57810-074	SERI	SERIAL NO.		
	A]	PPLICATION					ļ	
				APPLICANT Isao Hasegawa, et al.				
(PTO-1449)				FILING DATE September 11, 200	FILING DATE GROUP September 11, 2003			
U.S. PATENT DOCUMENTS								
EXAMINER'S	ſ	Document Number	Publication Da		Name of Patentee or Applicant of Cited Pages,			
INITIALS	CITE NO.	Number-Kind Code2 (if known)	MM-DD-YYY)	Document		Relevant Passages or Relevant Figures Appear		
		US						
		US	-					
	ļ	US	 					
	 	us	 					
	<u> </u>	US						
		US						
		US						
	L	US	ļ					
	! 	US						
	}	US						
		US	 	 				
	 	US						
	.		FOREIGN P.	ATENT DOCUMENTS				
EXAMINER'S INITIALS		Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Column Lines Where	s, Translation	Translation	
INTIALS	NO.	Country CodesNumber 4-Kind Codes (if known)			Relevant Figure Appear			
						Yes	No	
		JP P2002-93702A	03/29/2002	SANYO ELECTRIC CO LTD		(Japan w/English Abstract)		
		JP P2001-189458A	07/10/2001	SANYO ELECTRIC CO LTD		(Japan w/English Abstract)		
ļ		1	 					
	 	ļ		 			 	
	L	OTHER	ART (Including Auti		l tc.)			
EXAMINER'S INITIALS INITIALS INITIALS INITIALS INITIALS Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.								
		"Large Grain Poly-Si TFTs by Scanning CW Laser Crystallization," Hara et al. AM-LCD '02, Digest of Technical Papers, July 10-12, 2002 pp. 227-230						
Extended Abstracts (The 48th Spring Meeting, 2001); The Japan Society of Applied Physics and Related Societies. JSAP Catalog Number: AP 011109-02 (03/28/2001) pg. 900								
21st Century Version "A Handbook of Applied Forming for Thin Film," April 22, 2003								
EXAMINER				DATE CONSIDERED				

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.